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Page 2

Amendments to the Specification:

Please add the following new paragraph on page 4, line 3:

--One embodiment includes a maskless optical setup to generate interference patterns within selected areas of a photosensitive material, without the need of any physical mask to delimit or delimitate the spatial extent of the register of the interference pattern, ensuring that the surrounding area is not affected by light. The device may ensure that the time needed to register all the design polygonal patterns (that build up the complete optical device) is linearly proportional to the number of colors specified for the reference geometry and not to the area or to the number of pixels within the overall area of the optical device. The device may be based on the Scheimpflug and Hinge conditions, ensuring adequate superposition between different optical beams in an imaging configuration. The device optical configuration may be based on two object physical locations and two optical channels. The device optical configuration may be based on one object physical location and two optical channels. The device optical configuration may be based on one object physical location and one optical channel.--